File View Edit Tools Window Help

Drafts
Pending
Active
L1: (7259) cmp.clm. or (chemical adj mechanic
L2: (299) 1 and optical.clm.
L3: (245) 2 and light
L4: (177) 3 and (light or radiat$4 or wavelen
L5: (61) 4 and (material or optical$2 or lay
L6: (32) 5 and (optical$2 near (layer$1 or ma
L7: (38329) optical$2 adj3 (layer or material
L8: (662) 7 and (cmp or (chemical adj mechani
L9: (601) 8 and (light or radiation or wavele
L10: (307) 9 and (endpoint or stop$4)
L11: (284) 10 and remov$4
L12: (203) 11 and optical.clm.
L13: (102) 12 and (polish$4.clm. or planariz$
L14: (80) 13 and (endpoint or detect$3)
L15: (5) 14 and (optical$3 adj (material or l
Failed
Saved
(0) ("(thinadjfilm)nearresistor").PN.
(0) ("(thinadjfilm)nearresistor").PN.

14 and (optical$3 adj (material or layer)).clm.

U	I	PT	P	Document ID	Issue Dat	Pages	Title	Current US	Current XR	Retrieval	Inventor	R	C			
				US 20020135778	20020926	11	Fabrication of precision optics using	356/515			Folta, James A. et al.	☑				
				US 20020037600	20020328	41	Method of manufacturing electro-optical apparat	438/30	438/57; 438/78		Hirabayashi, Yukiya	☑				
				US 6661025 B2	20031209	40	Method of manufacturing electro-optical apparat	257/53	257/72; 438/149;		Hirabayashi, Yukiya	☑				
				US 6285035 B1	20010904	20	Apparatus for detecting an endpoint polishing l	250/559.22	250/559.4		Taravade, Kunal N.	☑				
				US 6074517 A	20000613	17	Method and apparatus for detecting an endpoi	156/345.13	250/338.1; 257/E21.23		Taravade, Kunal N.	☑				

Drafts
Pending
Active
  L1: (354838) detector or endpoint
  L2: (25112) 1 and cmp or (chemical adj mechan
  L3: (6499) 2 and (CMP.clm. or (chemical adj m
  L4: (2240) 3 and (light or optical)
  L5: (1479) 4 and removing
  L6: (260) 5 and light.clm.
  L7: (150) 6 and optical
  L8: (78) 7 and (cu or copper or NiFe or CoNiF
  L9: (54) 8 and remov$3.clm.
  L10: (54) 9 and light.clm.
  L11: (15) 10 and (endpoint$1.clm. or stop$4.c
Failed
Saved
  (0) ("(thinadjfilm)nearresistor").PN.
  (0) ("(thinadjfilm)nearresistor").PN.
  (150130) thin adj film
  (14857) (thin adj film) and resistor
  (2054) ((thin adj film) and resistor) and ((t
  (1735) (((thin adj film) and resistor) and ((

10 and (endpoint$1.clm. or stop$4.clm.)

U	PT	P	Document ID	Issue Dat	Pages	Title	Current OR	Current XR	Retrieval	Inventor	S	C				
			US 20040012089	20040122	48	Materials and methods for forming hybrid orga	257/750			Rantala, Juha T. et al.	✓					
			US 20030224596	20031204	13	Method and system for improving the manufactu	438/637			Marxsen, Gerd et al.	✓					
			US 20030213558	20031120	11	Chemical mechanical polishing endpoint dete	156/345.13	156/345.12		Basol, Bulent et al.	✓					
			US 20030184732	20031002	22	System and method of broad band optical end	356/72	356/300		Katz, Vladimir et al.	✓					
			US 20030153246	20030814	33	In-situ endpoint detect for non-transparent pol	451/8			Desai, Mukesh et al.	✓					
			US 20030066548	20030410	17	Inline monitoring of pad loading for CuCMP a	134/34	156/345.12 ;		Chopra, Dinesh et al.	✓					
			US 20030032209	20030213	24	Methods of fabricating optoelectronic IC modul	438/22	438/29		Yeh, Jang-Hun et al.	✓					
			US 20020173225	20021121	9	Chemical mechanical polishing endpoint dete	451/5	451/41; 451/6		Wang, Yuchun et al.	✓					
			US 20020002029	20020103	18	Polishing method and apparatus	451/41			Kimura, Norio et al.	✓					
			US 6476886 B2	20021105	18	Method for assembling a tiled, flat-panel micro	349/73	349/122; 349/74		Krusius, J. Peter et al.	✓					
	✓		US 6214734 B1	20010410	20	Method of using films having optimized optica	438/692	438/16; 438/959		Bothra, Subhas et al.	✓					